

Notice of References Cited	Application/Control No. 10/765,100	Applicant(s)/Patent Under Reexamination SHIN, JOHNGEON	
	Examiner Mai-Huong Tran	Art Unit 2818	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Shibata et al., Semiconductor Element, US 2002/0125491 A1, Pub. Date 09/12/02.
	V	Sone et al., Method for Growing High Quality Group-III Nitride Thin Film by Metal Organic Chemical Vapor Deposition, US 2002/0192373 A1, Pub. Date 12/19/02.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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